

NANYANG
TECHNOLOGICAL
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MA2011 - Part II

Mechatronics Systems Interfacing

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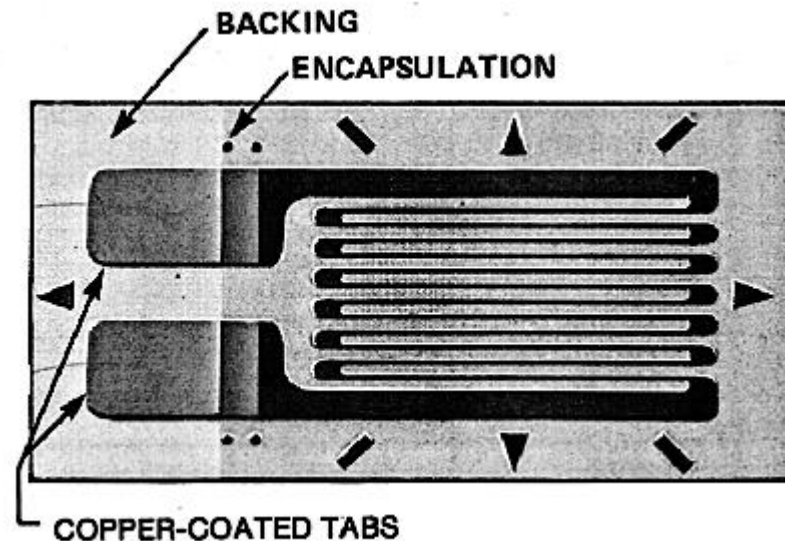
Strain gauges

resistance strain gauges

force measurements

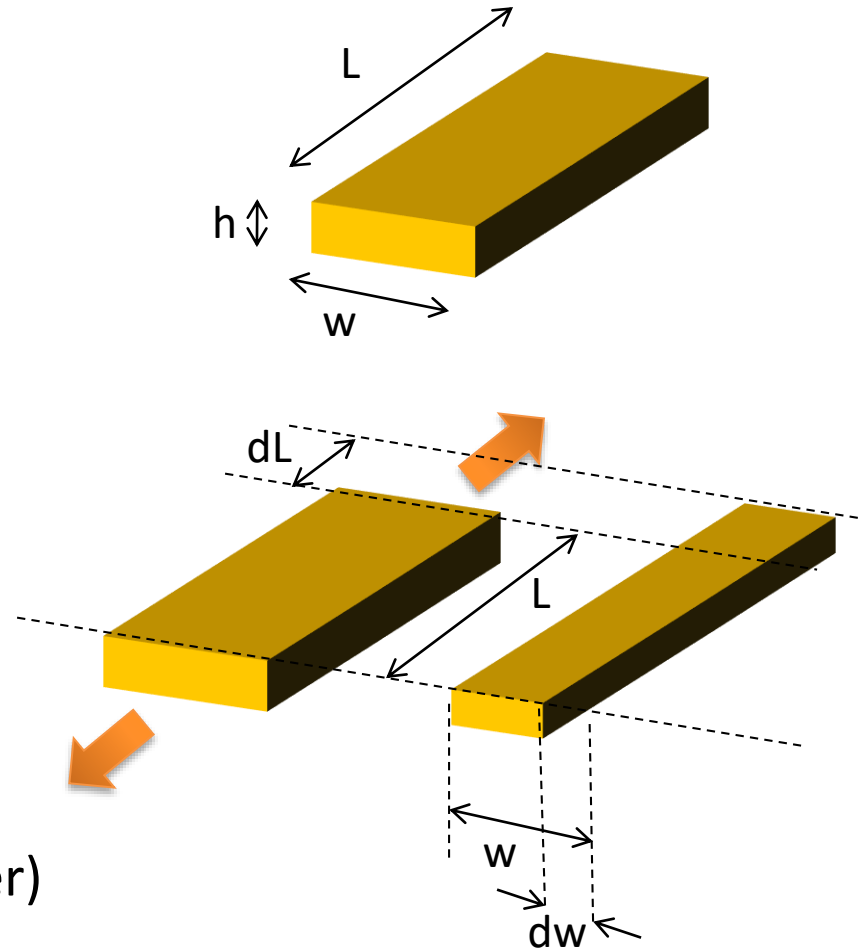
stress/strain measurements

- strain measurements are important to determine safe loading conditions of mechanical structures
 - stress/force measurements are typically derived indirectly from strain/displacement measurements
- electrical resistance strain gauges
 - thin metal foil
 - typically constantan
 - patterned onto plastic backing material
 - bonded onto mechanical structures
 - stress is inferred from solid mechanics principles



resistance strain gauges

- what is strain?
 - $S := dL/L$ quantifies the amount of deformation of a body
 - non-dimensional
 - defined as a relative change (dL/L)
 - typical materials undergo from 'microstrains' 10^{-6} (ppm) up to a few %
 - positive (tensile strain) or negative (compression) values
 - Poisson's ratio
 - typically ν : 0.3 (steel) \rightarrow 0.5 (rubber)
- $$\nu := \frac{\text{lateral strain}}{\text{axial strain}}$$



resistance strain gauges

- resistance of a rectangular conductor

$$R = \rho \frac{L}{A}$$

$$A = wh$$

– differential form

$$\frac{dR}{R} = \frac{d\rho}{\rho} + \frac{dL}{L} - \frac{dA}{A}$$

$$\frac{dA}{A} = \frac{dw}{w} + \frac{dh}{h}$$

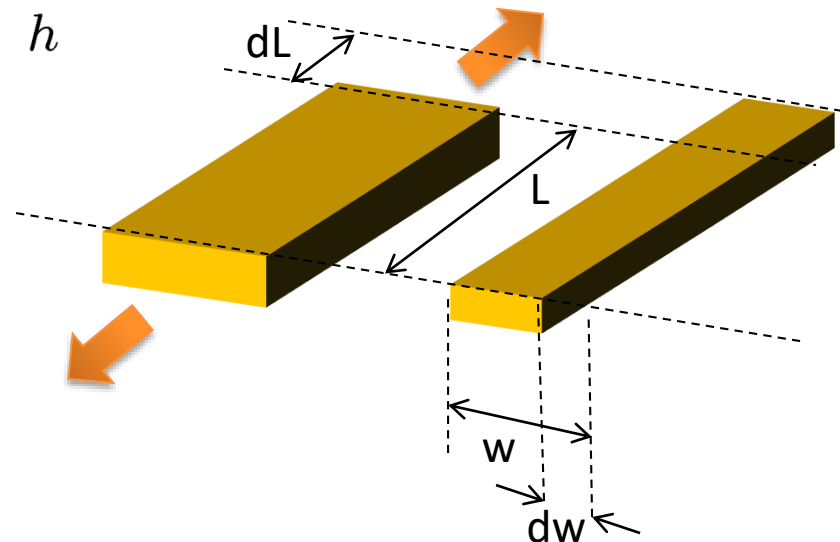
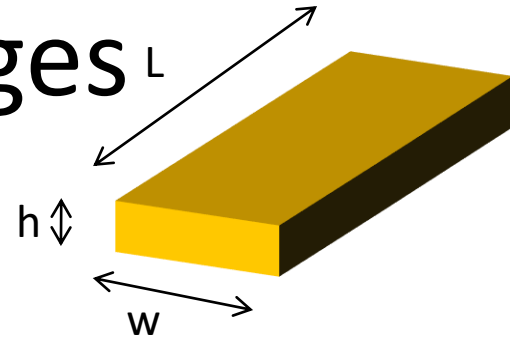
– axial strain

$$S := \frac{dL}{L}$$

– lateral strain

$$\frac{dw}{w} = \frac{dh}{h} = -\nu \frac{dL}{L} = -\nu S$$

$$\frac{dR}{R} = \frac{d\rho}{\rho} + \frac{dL}{L} - \left(\frac{dw}{w} + \frac{dh}{h} \right)$$



resistance strain gauges

$$\frac{dR}{R} = \frac{d\rho}{\rho} + \frac{dL}{L} - \left(\frac{dw}{w} + \frac{dh}{h} \right)$$

$$= \frac{d\rho}{\rho} + (1 + 2\nu)S$$

$$= \left(\underbrace{\frac{d\rho}{\rho} \frac{1}{S}}_{\text{piezoresistivity}} + 1 + 2\nu \right) S$$

$$\frac{dR}{R} = \mathcal{G} S$$

- gauge factor:

$$\mathcal{G} := \underbrace{\frac{dR}{R} \frac{1}{S}}_{\text{piezoresistivity}} = \frac{1}{R} \frac{\partial R}{\partial S} = \frac{d\rho}{\rho} \frac{1}{S} + 1 + 2\nu$$

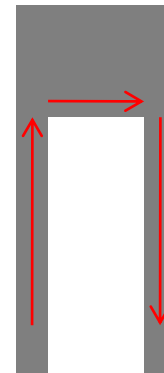
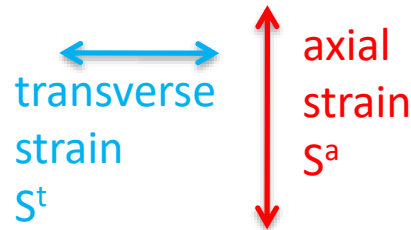
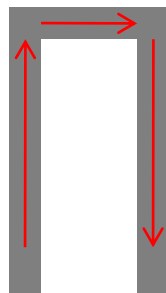
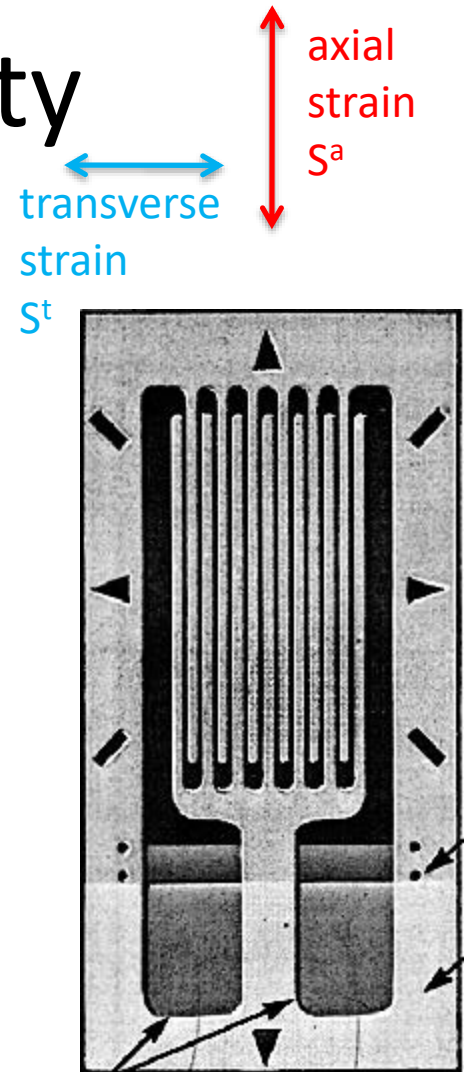
$$dR = dR^S := \frac{\partial R}{\partial S} S$$

NOTE: here we are only considering changes of resistance due to strain $dR = dR^S$

Material	Gauge Factor
Nickel	-12.6
Manganese	+0.07
Nicrome	+2.0
Constantan	+2.1
Soft Iron	+4.2
Carbon	+20
Platinum	+4.8

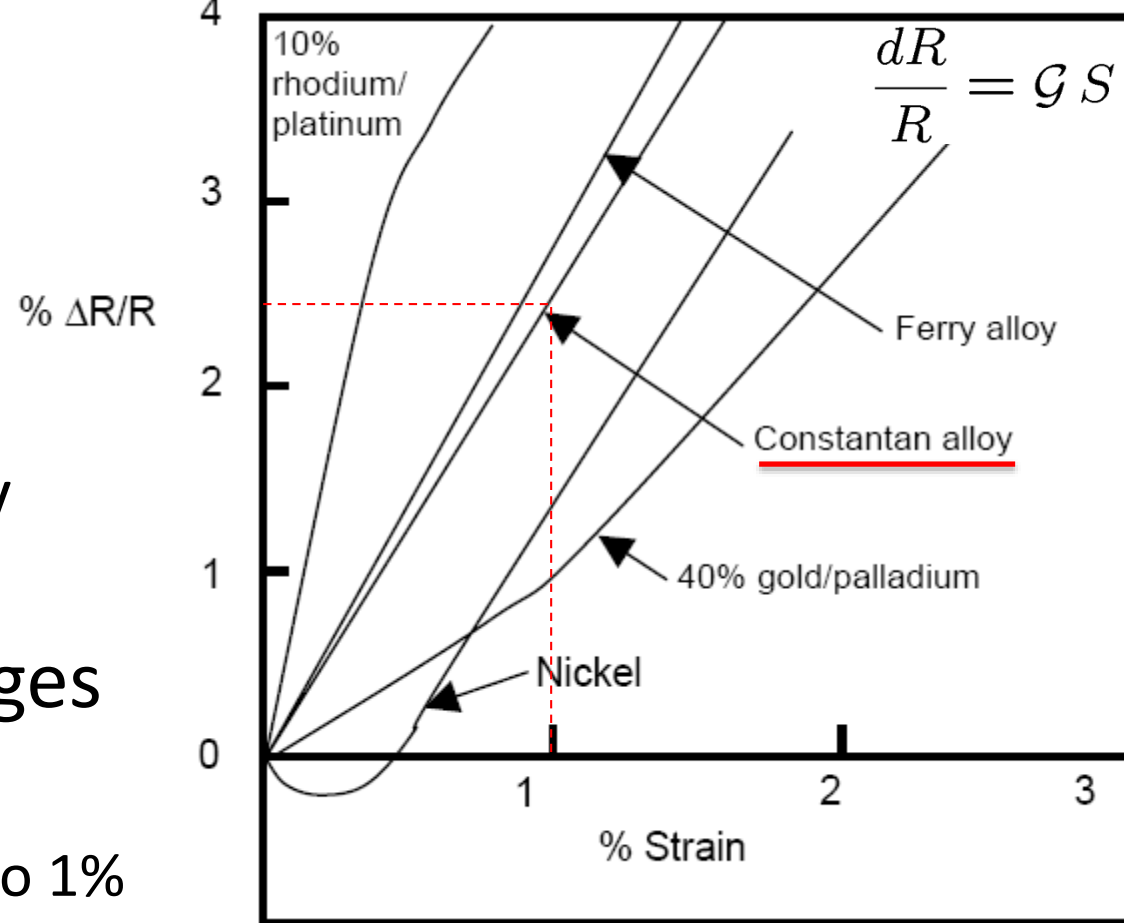
transverse sensitivity

- $dR = R_0 \mathbf{G} \mathbf{S}$
 - the larger R_0 , the larger dR
 - long and thin wires allow larger R_0
 - wires must be aligned with axial strain S^a
 - practically, long wires are assembled in the form of a serpentine
 - end-loops
 - are aligned with the transverse axis
 - made thicker to reduce sensitivity to S^t



materials

- best materials
 - constantan, ferry alloys
- typical strain ranges
 - S : $1\text{-}10^4 \mu\text{S}$
 - i.e. from 1ppm to 1%
 - $G \sim 2$
 - dR/R is in the same order of magnitude as S
 - **challenge**: detecting small resistance changes



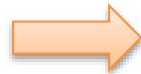
a numerical example

- $dR = R = \mathbf{G} S$
 - $\mathbf{G} \sim 2$
 - $R_0 \sim 100\text{-}1,000 \, \Omega$
 - strain in the order of $10\text{-}10^4 \, \mu\text{S}$ (micro-strain)
 - strain is adimensional
 - $1 \, \mu\text{S} = 10^{-6}$ (e.g. $1\mu\text{m}/\text{m}$)
- $dR = (100 \, \Omega) \times 2 \times (100 \, \mu\text{S}) = 0.02 \, \Omega$
 - transverse sensitivity in the order of 1%
 - how do we sense such small changes?

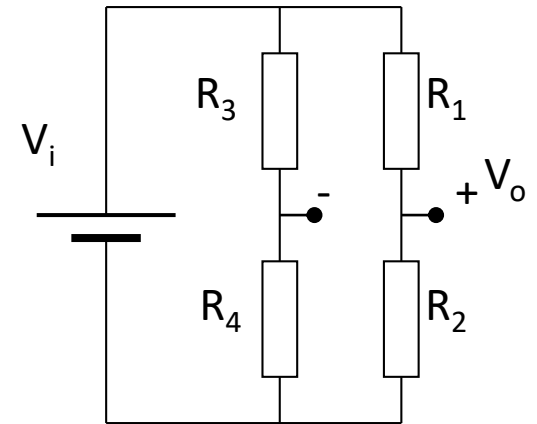
Wheatstone bridge

- bridge equations

$$\begin{cases} \frac{V^+}{V_i} = \frac{R_2}{R_1 + R_2} \\ \frac{V^-}{V_i} = \frac{R_4}{R_3 + R_4} \end{cases}$$



$$\frac{V_o}{V_i} = \frac{R_2}{R_1 + R_2} - \frac{R_4}{R_3 + R_4}$$



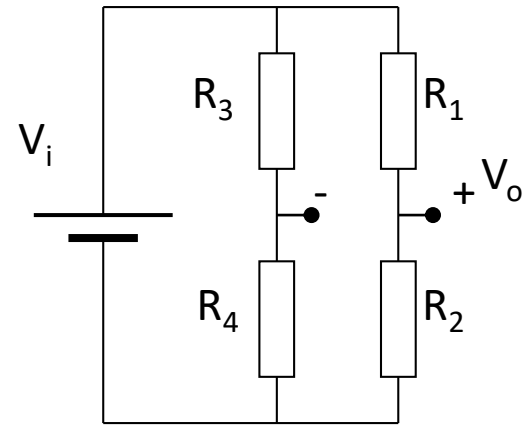
- bridge balance condition:

$$V_o = 0 \quad \Leftrightarrow \quad R_1 R_4 = R_2 R_3$$

(product of opposite sides)

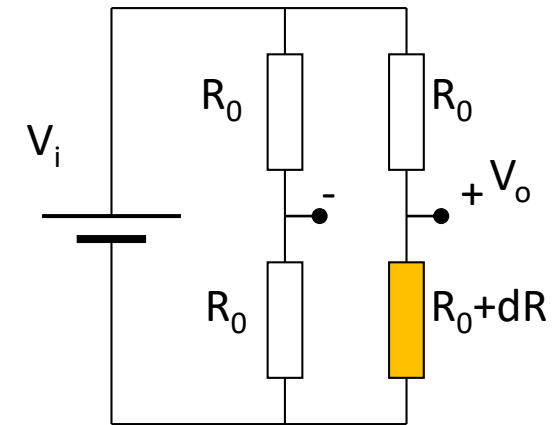
Wheatstone bridge: 1st order approximation

- bridge sensitivity
 - when $R_1=R_2$ and $R_3=R_4$
 - NOTE: this also implies balance
 - first order approximation
 - acceptable up to few % S
 - NOTE: 1% S = $10^4 \mu S$



$$\frac{dV_o}{V_i} = \frac{1}{4} \left(\frac{dR_2}{R_2} - \frac{dR_1}{R_1} + \frac{dR_3}{R_3} - \frac{dR_4}{R_4} \right)$$

example: quarter-bridge



one-gauge bridge

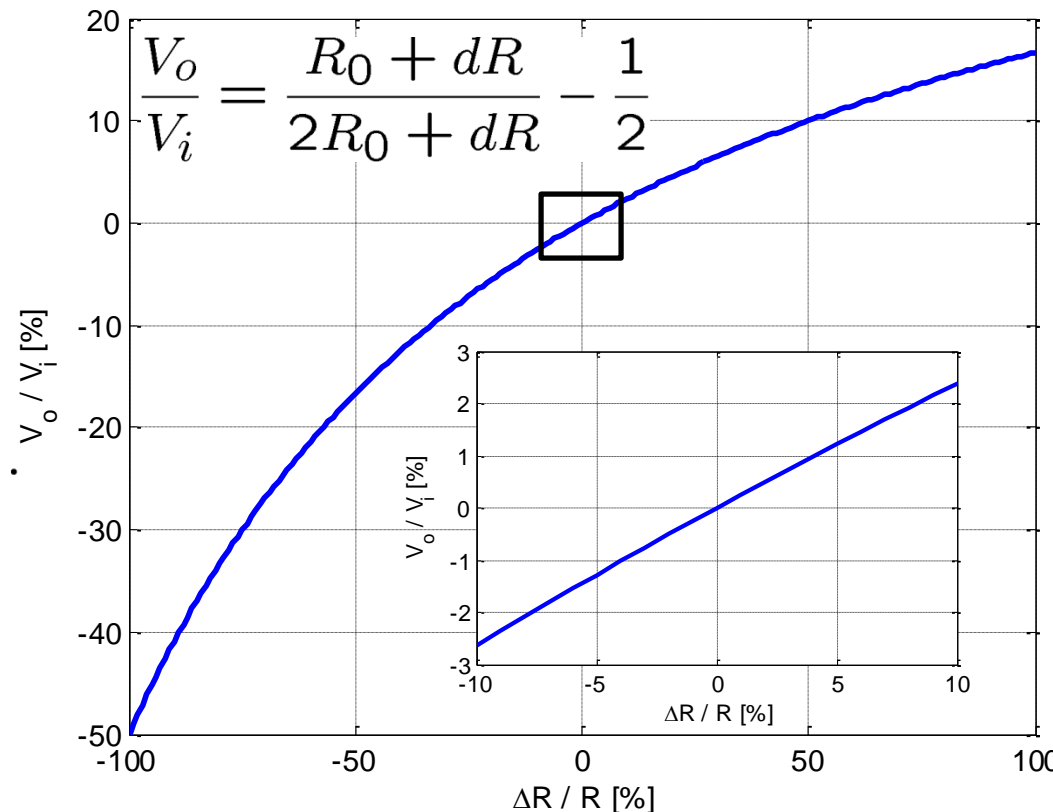
- consider
 - $R_1 = R_3 = R_4 = R_0$
 - $R_G = R_0 + dR$
- bridge output

$$\frac{dV_o}{V_i} = \frac{R_0 + dR}{2R_0 + dR} - \frac{1}{2}$$

– Taylor expansion

$$\frac{dV_o}{V_i} = \frac{1}{4} \frac{dR}{R_0} - \frac{1}{4} \frac{dR^2}{R_0^2} + \dots h.o.t. \dots$$

$$\frac{dV_o}{V_i} \simeq \frac{1}{4} \frac{dR}{R_0} = \frac{1}{4} \mathcal{G} S$$

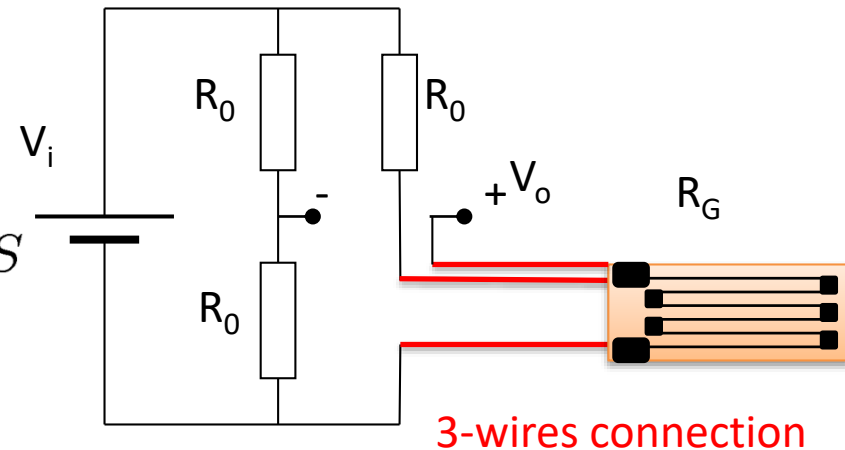
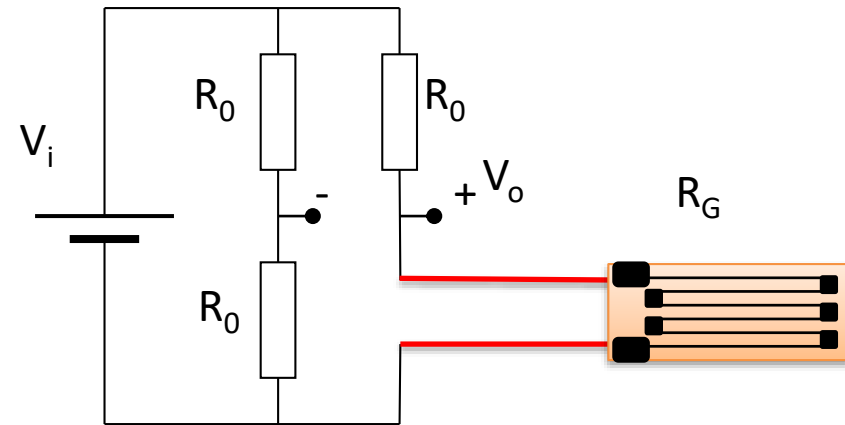
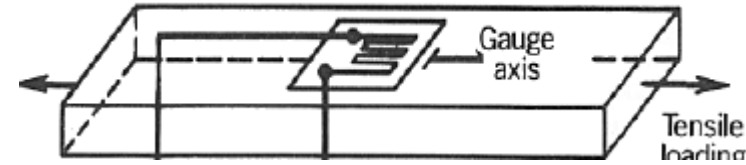


quarter-bridge

- 2-wire connection
 - R_w : long wires resistance
 - as high as few ohms
 - temperature dependent
 - unbalancing effects
- **3-wire connection**
 - 3rd wire: no current!!!
 - balanced bridge
 - attenuated gauge factor

$$\frac{V_o}{V_i} = \frac{1}{4} \frac{dR}{R_0 + R_w} = \frac{1}{4} \frac{R_0}{R_0 + R_w} \frac{dR}{R_0} = \frac{1}{4} G^* S$$

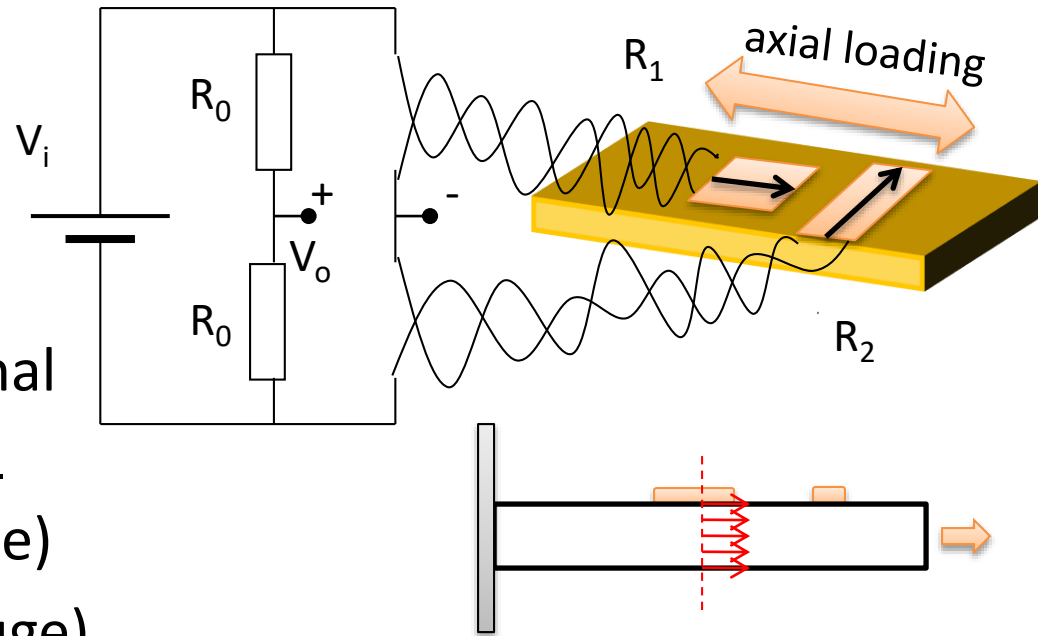
$$G^* = G \frac{R_0}{R_0 + R_w} \leq G$$



temperature compensation

- dummy gauges**

- mounted in close thermal contact but not bonded
- $R_1 = R_0 + dR_1$ (strain gauge)
- $R_2 = R_0 + dR_2$ (dummy gauge)



$$\begin{cases} dR_1 = \frac{\partial R_1}{\partial S} S + \frac{\partial R_1}{\partial T} dT \\ dR_2 = \frac{\partial R_2}{\partial T} dT \end{cases} \quad \frac{\partial R_1}{\partial T} dT = \frac{\partial R_2}{\partial T} dT \quad \left. \begin{array}{l} \text{technologically} \\ \text{similar gauges} \\ \text{in thermal contact} \end{array} \right\}$$

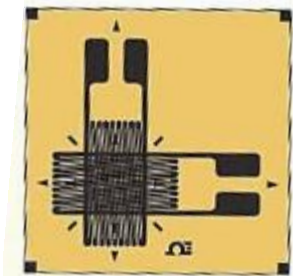
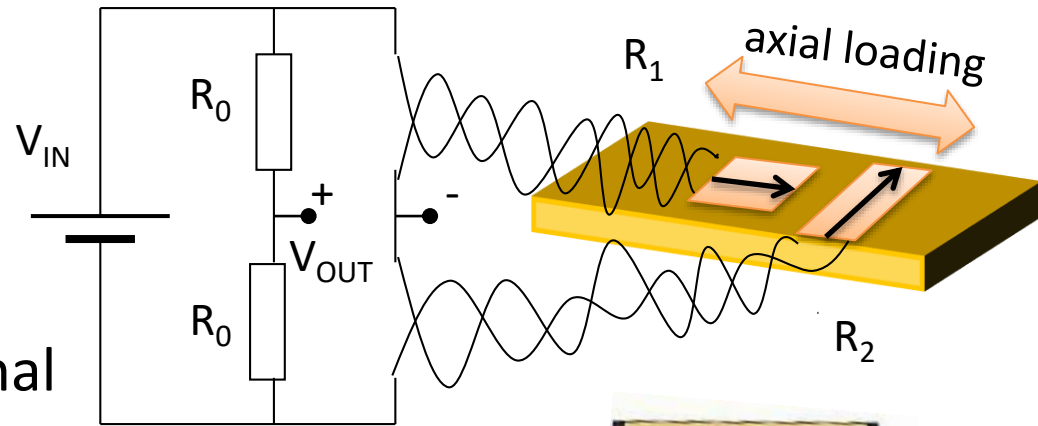
$$\frac{dV_o}{V_i} = \frac{1}{4} \left(\frac{dR_1}{R_0} - \frac{dR_2}{R_0} \right) = \frac{1}{4R_0} \left(\frac{\partial R_1}{\partial S} S + \frac{\partial R_1}{\partial T} dT - \frac{\partial R_2}{\partial T} dT \right)$$

$$\frac{dV_o}{V_i} = \frac{1}{4R_0} \left(\frac{\partial R_1}{\partial S} S \right) = \frac{1}{4} \mathcal{G} S$$

temperature compensation

- **Poisson gauges**

- mounted in close thermal contact and bonded
- $R_1 = R_0 + dR_1$ (strain gauge)
- $R_2 = R_0 + dR_2$ (poisson gauge)



$$\begin{cases} dR_1 = \frac{\partial R_1}{\partial S} S + \frac{\partial R_1}{\partial T} dT \\ dR_2 = -\nu \frac{\partial R_2}{\partial S} S + \frac{\partial R_2}{\partial T} dT \end{cases} \quad \begin{cases} \frac{\partial R_1}{\partial T} dT = \frac{\partial R_2}{\partial T} dT \\ \frac{\partial R_1}{\partial S} = \frac{\partial R_2}{\partial S} \end{cases}$$

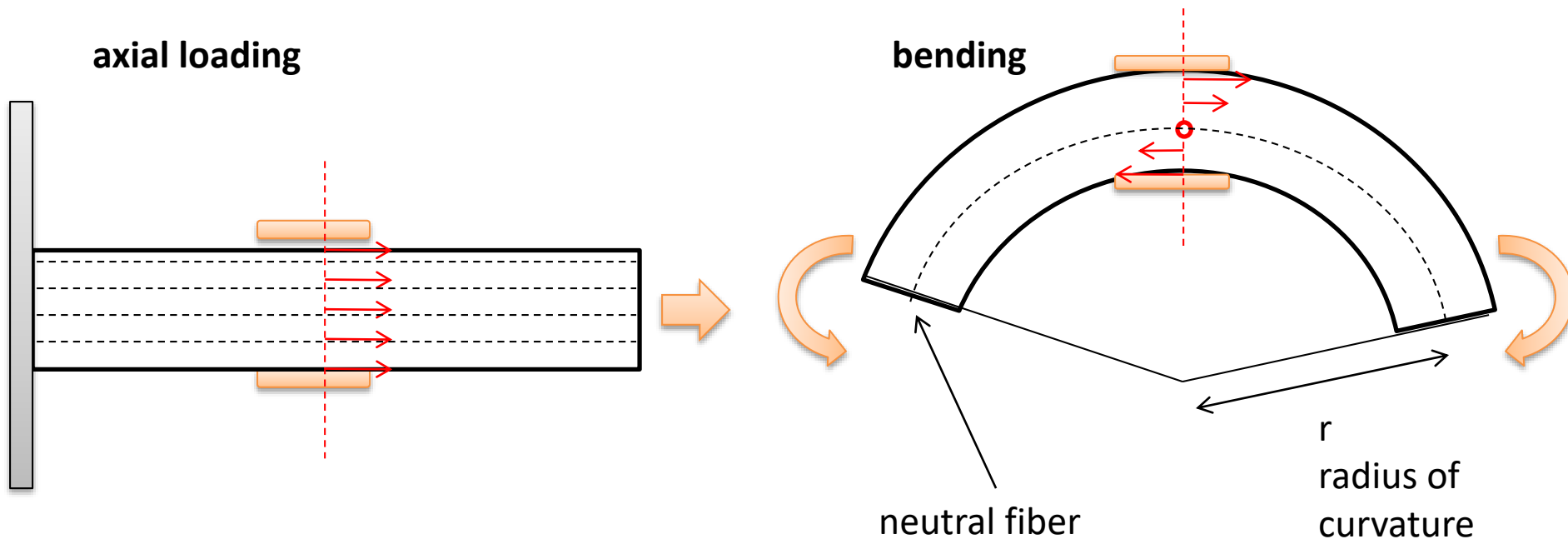
technologically similar gauges, bonded together, in thermal contact

$$\frac{dV_o}{V_i} = \frac{1}{4} \left(\frac{dR_1}{R_0} - \frac{dR_2}{R_0} \right) = \frac{1}{4R_0} \left(\frac{\partial R_1}{\partial S} S + \frac{\partial R_1}{\partial T} dT + \nu \frac{\partial R_2}{\partial S} S - \frac{\partial R_2}{\partial T} dT \right)$$

$$\frac{dV_o}{V_i} = \frac{1}{4R_0} \left(\frac{\partial R_1}{\partial S} (1 + \nu) S \right) = \frac{1}{4} \mathcal{G} (1 + \nu) S$$

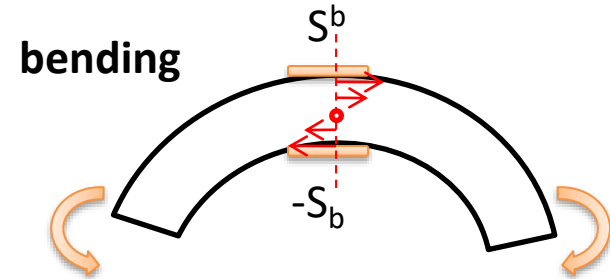
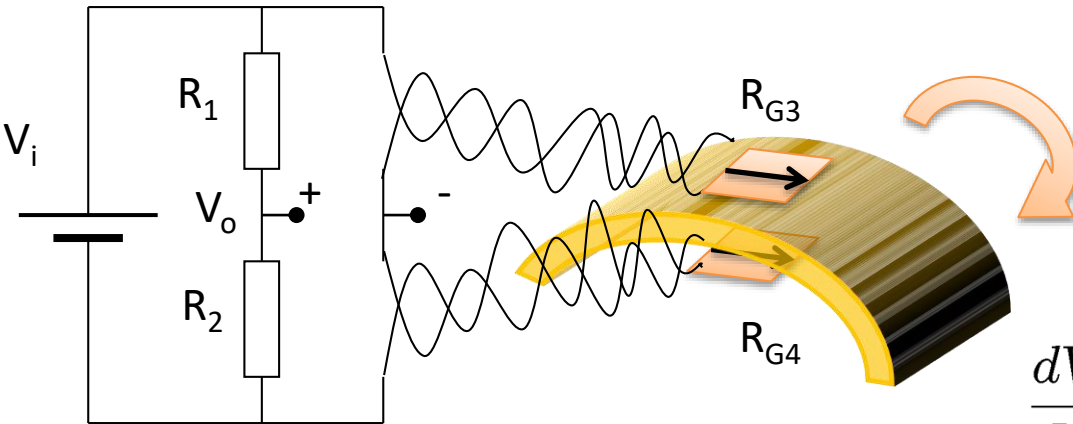
half bridge

- two active strain gauges
 - enhancing the sensitivity of the bridge

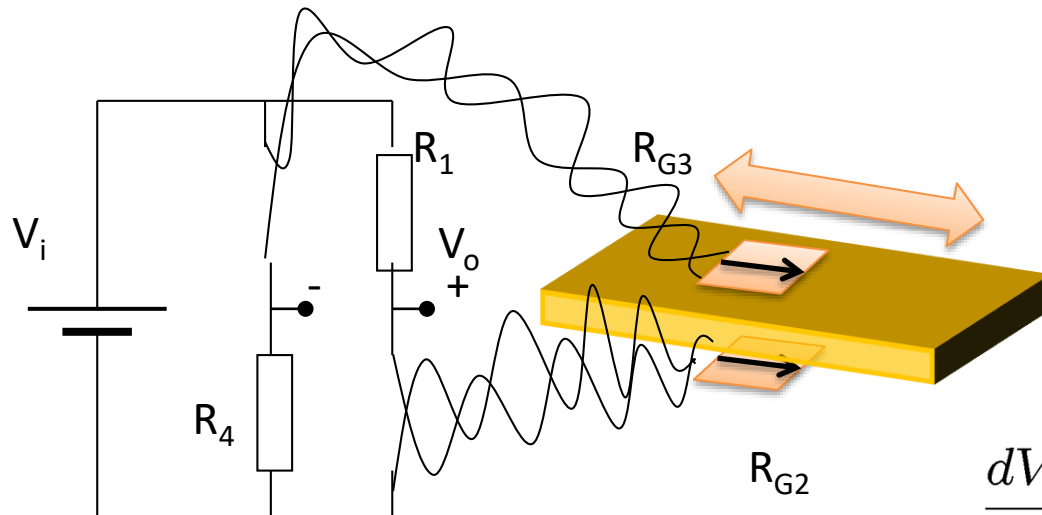


half-bridge

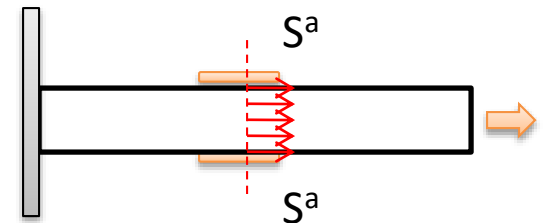
$$\frac{dV_o}{V_i} = \frac{1}{4} \left(\frac{dR_2}{R_2} - \frac{dR_1}{R_1} + \frac{dR_3}{R_3} - \frac{dR_4}{R_4} \right)$$



$$\frac{dV_o}{V_i} = \frac{1}{4} \left(\frac{dR_3}{R_3} - \frac{dR_4}{R_4} \right) = \frac{1}{2} \mathcal{G} S^b$$



axial loading



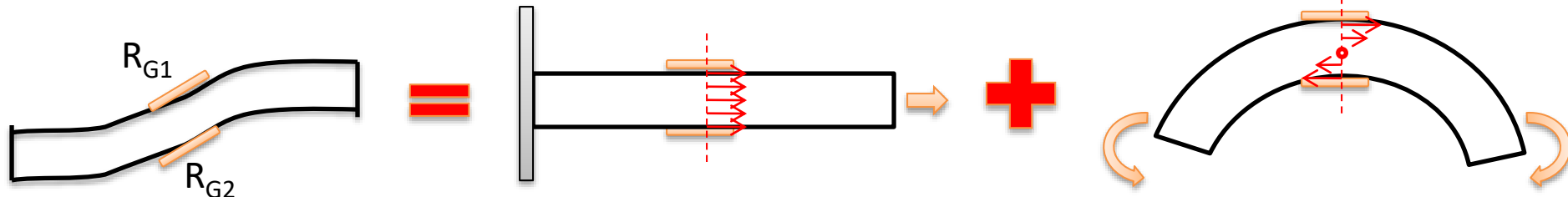
$$\frac{dV_o}{V_i} = \frac{1}{4} \left(\frac{dR_2}{R_2} + \frac{dR_3}{R_3} \right) = \frac{1}{2} \mathcal{G} S^a$$

apparent strain: loading condition

- apparent strain is manifested as any change in gauge resistance which is not due to the strain being measured
- for example, combinations of:
 - different mechanical loading

- $S_1 = S^a + S^b$

- $S_2 = S^a - S^b$



apparent strain: thermal effects

- resistance changes might be due to a combination of strain and temperature

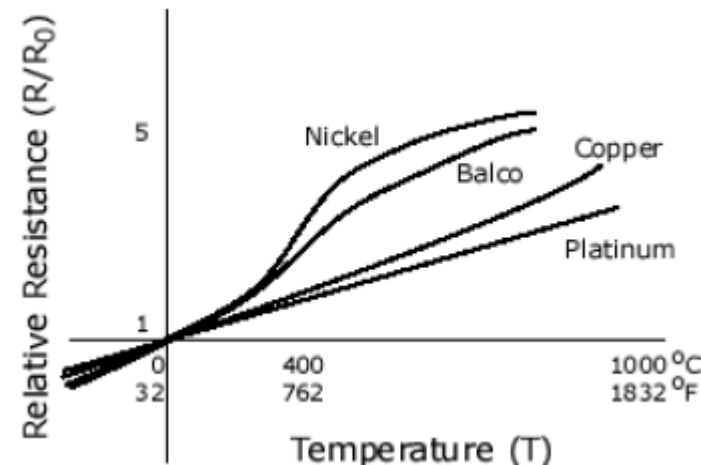
$$dR = \frac{\partial R}{\partial S} S + \frac{\partial R}{\partial T} dT = \frac{\partial R}{\partial S} \left(S + \overbrace{\left(\frac{\partial R}{\partial S} \right)^{-1} \frac{\partial R}{\partial T} dT}^{\text{apparent strain } S^T} \right)$$

- apparent strain due to temperature

- notation: dR^T is the resistance change solely due to temperature

$$S^T := \left(\frac{\partial R}{\partial S} \right)^{-1} \frac{\partial R}{\partial T} dT = \underbrace{\frac{1}{G} \frac{1}{R} \frac{\partial R}{\partial T}}_{2,000 \mu S / K^{-1}} dT = \frac{1}{G} \frac{dR^T}{R}$$

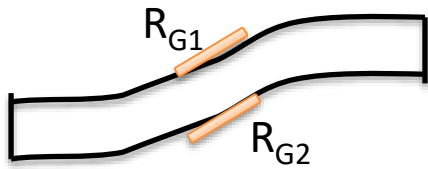
4,000 ppm / K⁻¹ [temperature coefficient]



example: half-bridge (1/2)

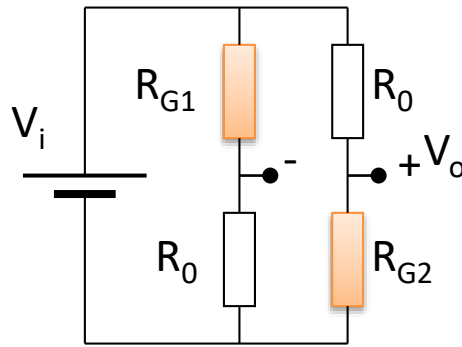
- ultimately, sensitivity to loading condition and temperature is determined by the electrical configuration

$$S_{G1} = S^a + S^b + S^T$$



$$S_{G2} = S^a - S^b + S^T, \text{ axial strain}$$

– can compensate bending but not temperature!

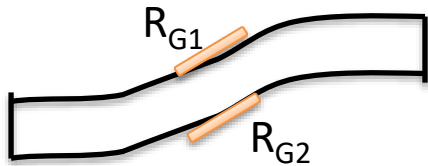


$$\begin{aligned} \frac{dV_o}{V_i} &= \frac{1}{4} \mathcal{G} (S_{G1} + S_{G2}) \\ &= \frac{1}{2} \mathcal{G} (S^a + S^T) \end{aligned}$$

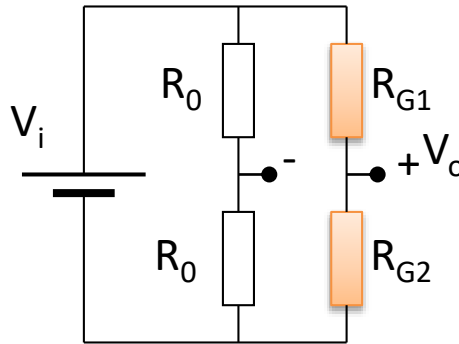
example: half-bridge (2/2)

- ultimately, sensitivity to loading condition and temperature is determined by the electrical configuration

$$S_{G1} = S^a + S^b + S^T$$



$$S_{G2} = S^a - S^b + S^T$$

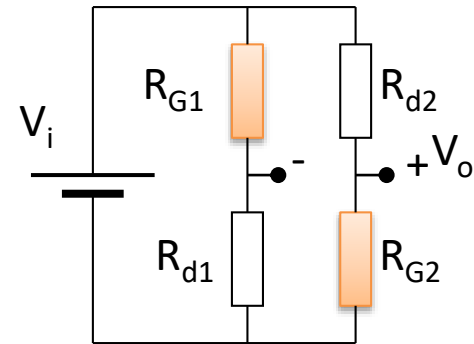
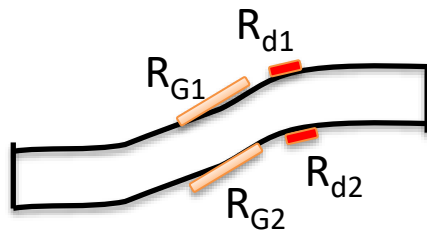


$$\begin{aligned} \frac{dV_o}{V_i} &= \frac{1}{4} \mathcal{G} (-S_1 + S_2) \\ &= \frac{1}{2} \mathcal{G} S^b \end{aligned}$$

- sensitive to bending strain
- compensate for axial strain and temperature

example: full-bridge (1/2)

- can sense axial strain
- can compensate for temperature and bending



$$S_{G1} = S^a + S^b + S^T$$

$$S_{G2} = S^a - S^b + S^T$$

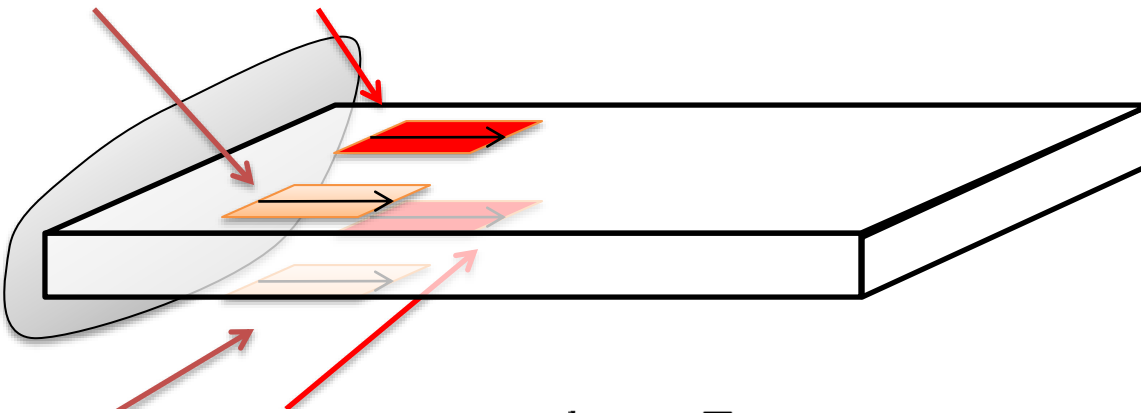
$$S_{d1} = S_{d2} = S^T$$

$$\frac{dV_o}{V_i} = \frac{1}{4} \mathcal{G} (S_{G1} - S_{d1} + S_{G2} - S_{d2}) = \frac{1}{2} \mathcal{G} S^a$$

example: full-bridge (2/2)

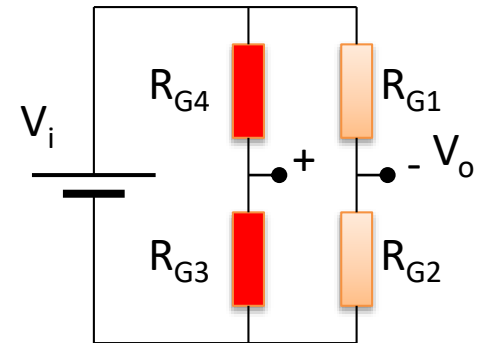
- can sense bending strain
 - maximum bridge sensitivity
- can compensate for temperature and axial strain

$$S_{G1} = S_{G3} = S^a + S^b + S^T$$



$$S_{G2} = S_{G4} = S^a - S^b + S^T$$

$$\frac{dV_o}{V_i} = \frac{1}{4} \mathcal{G} (S_{G1} - S_{G2} + S_{G3} - S_{G4}) = \mathcal{G} S^b$$



NOTE: these formulae only hold under the small-deformations assumption

example: cantilever beams

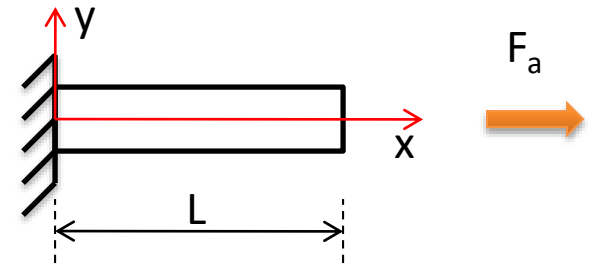
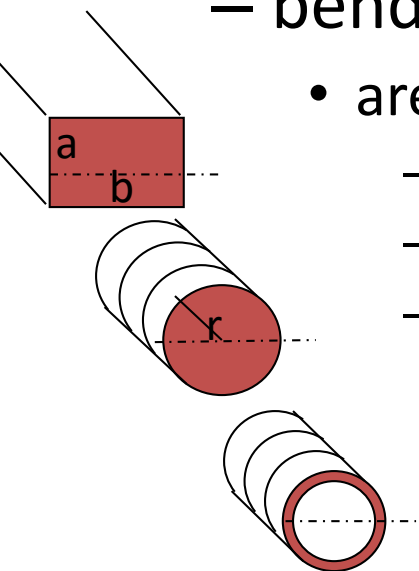
- longitudinal strain due to
 - axial loading (F_a)

- L: length
- t: thickness
- A: cross-section
- E: Young's module

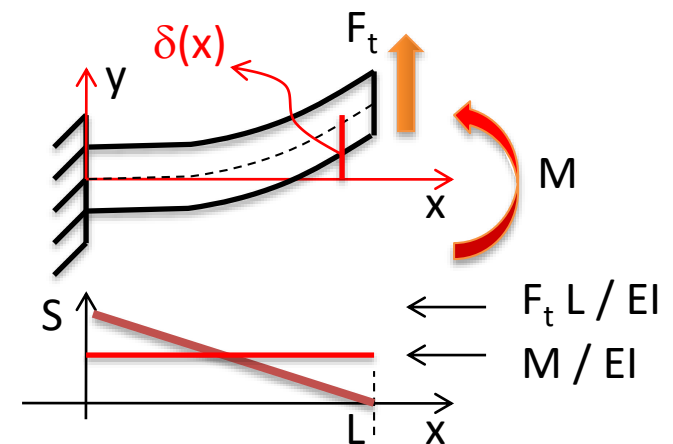
- bending (M, F_t)

- area moment of inertia I

- $I = ab^3 / 12$
- $I = \pi r^4 / 4$
- $I = \pi (r_{\max}^4 - r_{\min}^4) / 4$



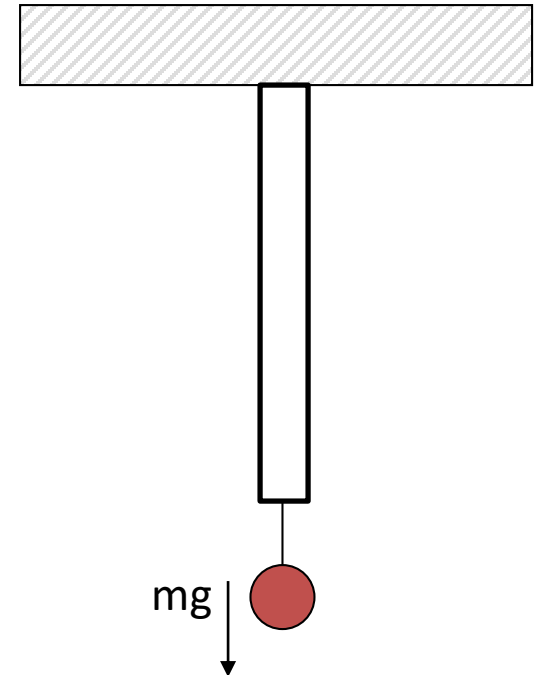
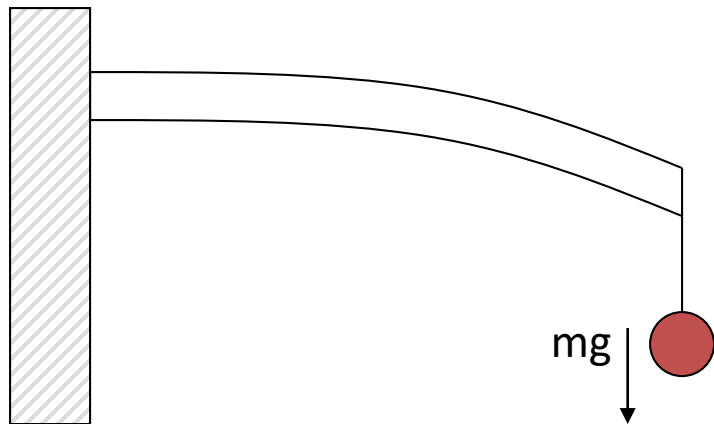
$$S_a = \frac{F_a}{EA}$$



$$S_b = -\frac{M + F_t(L - x)}{EI} \frac{t}{2}$$

measuring forces:

- you are given 2 identical strain-gauges
 - $dR/R = \mathbf{G} S$ where $\mathbf{G}=2$
- where/how would you place them, along the beam, to measure the weight of a mass m and
 - maximize sensitivity?
 - compensate for temperature changes?



bridge balancing

- so far, we assumed that the bridge was balanced when no stress was applied
 - in real life, that's never going to happen...
- reestablish balance by modifying arm resistors
 - $R_1 * R_3 = R_2 * R_4$
- (a) and (c) require
 - very low resistors (non practical)
 - in-series switches/contacts
 - unreliable extra resistance will be added
- (b) and (d) are the most suitable
 - much larger resistors can be used
 - the structure of the bridge is not modified
 - parallel insertion
- (d) is more general (balancing both sides)

